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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of:

Landon B. Vines et al.

Application No. 09/871,507

Filed: May 31, 2001

CMP POLISHER SUBSTRATE REMOVAL
CONTROL MECHANISM AND METHOD

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) Before the Examiner
)
) Group Art Unit 1746
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) October 9, 2001
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Associate P/A
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**ASSOCIATE POWER OF ATTORNEY AND
CORRESPONDENCE ADDRESS CHANGE**

Assistant Commissioner for Patents
Washington, D.C. 20231


Sir:

The undersigned attorney of record hereby requests that the correspondence address for
the above-captioned application be changed to the following:

I hereby certify that this correspondence is being deposited with the
United States Postal Service as first class mail in an envelope addressed
to the Assistant Commissioner for Patents, Washington, D.C. 20231 on:

Date of Deposit: October 9, 2001

Name of Registered Representative: L. Scott Paynter

Signature: 

Date of Signature: October 9, 2001

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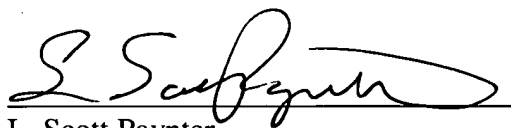
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Further, please recognize the following individuals as having associate power of attorney
in the above-referenced application:

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All of whom can be contacted at the new correspondence address.

Respectfully submitted,



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